Abstract

The invention relates to a carrier for a semiconductor wafer and the use of the carrier. The carrier has at least three protrusions on which the edge of the semiconductor wafer is supported so that the semiconductor wafer ends up essentially horizontal. The carrier does not make contact with the front side and the rear side of the semiconductor wafer, and the protrusions are shaped so that the edge of the semiconductor wafer is supported exclusively below an imaginary central plane in the center between the front side and the rear side of the semiconductor wafer. The carrier is preferably used in the treatment of semiconductor wafers at temperatures of at least 200°C.

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